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PATENTS  
9955/D01/Y01/AGS/LP



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s) : Mark Holst et al.  
Serial No. : 09/970,613  
Filed : October 4, 2001  
For : EFFLUENT GAS STREAM TREATMENT SYSTEM HAVING  
UTILITY FOR OXIDATION TREATMENT OF  
SEMICONDUCTOR MANUFACTURING EFFLUENT GASES  
Group Art Unit : 1764  
Customer No. : 41161

Mail Stop RCE  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

Sir:

In accordance with 37 C.F.R. §§ 1.56 and 1.97,  
applicants wish to call the attention of the Examiner to the  
following references:

U.S. Patent No. 4,296,079, Hauser  
U.S. Patent No. 4,935,212, Eberhard  
U.S. Patent No. 5,206,003, Imoto et al.  
U.S. Patent No. 5,292,704, Lester  
U.S. Patent No. 5,393,394, Ikeda et al.

U.S. Patent No. 5,877,391, Kanno et al.

Foreign Art Reference No. EP 0861683 A2 (EPO)

Foreign Art Reference No. EP 0885648 A1 (EPO)

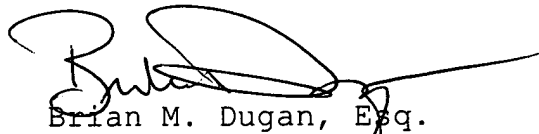
"Catalytic Decomposition System", Hitachi America, Ltd. Semiconductor Equipment Group- SCDS Gas Abatement Systems, <<http://www.hitachi.com/semiequipment/products/scds.html>>, pages 1-2, printed on 4/21/99.

"Kanken Techno detoxifier KT 1000 Venus", Crystec Technology Trading GmbH, <<http://www.crystec.com/ktcvenue.htm>>>, pages 1-4, printed on 7/27/99.

These references are also listed on the accompanying Information Disclosure Statement (Form PTO-1449).

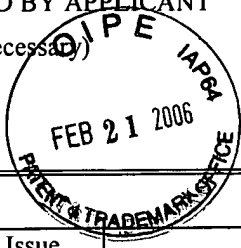
Consideration of the foregoing in relation to this patent application is respectfully requested.

Respectfully Submitted,



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Dated: 2/21/06  
Tarrytown, New York

U.S. Department of Commerce, Patent and Trademark Office  <b>LIST OF RELEVANT ART CITED BY APPLICANT</b> (Use several sheets if necessary)				Docket No.: 9955/D01/Y01/AGS/LP		Serial No.: 09/970,613	
				Applicants: Mark Holst et al.			
				Filing Date: October 4, 2001		Group: 1764	

U.S. Patent Documents							
*Examiner Initial	Document Number	Issue Date	Name	Class	Subclass	Filing Date If Appropriate	
	US-1	4,296,079	10/20/81	Hauser			
	US-2	4,935,212	06/19/90	Eberhard			
	US-3	5,206,003	04/27/93	Imoto et al.			
	US-4	5,292,704	03/08/94	Lester			
	US-5	5,393,394	02/28/95	Ikeda et al.			
	US-6	5,877,391	03/02/99	Kanno et al.			
	US-7						
	US-8						
	US-9						
	US-10						
	US-11						

Foreign Patent Documents							Translation	
	Document Number	Date	Country	Class	Subclass	Yes	No	
	F-1	EP 0861683 A2	09/02/98	EPO		X		
	F-2	EP 0885648 A1	12/23/98	EPO		X		
	F-3							
	F-4							
	F-5							

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)	
OT-1	"Catalytic Decomposition System", Hitachi America, Ltd. Semiconductor Equipment Group- SCDS Gas Abatement Systems, < <a href="http://www.hitachi.com/semiequipment/products/scds.html">http://www.hitachi.com/semiequipment/products/scds.html</a> >, pages 1-2, printed on 4/21/99.
OT-2	"Kanken Techno detoxifier KT 1000 Venus", Crystec Technology Trading GmbH, < <a href="http://www.crystec.com/ktcvenue.htm">http://www.crystec.com/ktcvenue.htm</a> >, pages 1-4, printed on 7/27/99.
OT-3	

Examiner	Date Considered
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**\*EXAMINER:** Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.